PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q79450

Masayuki NAYA, et al.

Appln. No.: Unknown

Confirmation No.: Unknown

Group Art Unit: Unknown

Filed: January 29, 2004

Examiner: Unknown

For:

SENSOR CHIP, PROCESS FOR PRODUCING THE SAME, AND SENSOR USING

THE SAME

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §§ 1.97 and 1.98

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In accordance with the duty of disclosure under 37 C.F.R. § 1.56, Applicant hereby notifies the U.S. Patent and Trademark Office of the documents which are listed on the attached PTO/SB/08 A & B (modified) form and/or listed herein and which the Examiner may deem material to patentability of the claims of the above-identified application.

One copy of each of the listed documents, other than any U.S. patents and patent publications, is submitted herewith.

The present Information Disclosure Statement is being filed: (1) No later than three months from the application's filing date; (2) Before the mailing date of the first Office Action on the merits (whichever is later); or (3) Before the mailing date of the first Office Action after INFORMATION DISCLOSURE STATEMENT

U.S. Appln. No.: Q79450

filing a request for continued examination (RCE) under §1.114, and therefore, no Statement

under 37 C.F.R. § 1.97(e) or fee under 37 C.F.R. § 1.17(p) is required.

In compliance with the concise explanation requirement under 37 C.F.R. § 1.98(a)(3) for

foreign language documents, Applicant submits the following explanations:

An English language abstract, submitted herewith, constitutes a concise statement of

relevancy for Japanese Unexamined Patent Publication No. 11(1999)-200090.

The submission of the listed documents is not intended as an admission that any such

document constitutes prior art against the claims of the present application. Applicant does not

waive any right to take any action that would be appropriate to antedate or otherwise remove any

listed document as a competent reference against the claims of the present application.

The USPTO is directed and authorized to charge all required fees, except for the Issue

Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any

overpayments to said Deposit Account. A duplicate copy of this paper is attached.

Respectfully submitted,

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Comp	olete if Known
Application Number	Unknown
Confirmation Number	Unknown
Filing Date	January 29, 2004
First Named Inventor	Masayuki NAYA
Art Unit	Unknown
Examiner Name	Unknown
Attorney Docket Number	Q79450

			U.S.	PATENT DOCU	JMENTS
Examiner Initials*	Cite No.1	Document No	ımber	Publication Date MM-DD-YYYY	
		Number	Kind Code ² (if known)		Name of Patentee or Applicant of Cited Document
		US 20020089617	A1	07-11-2002	Tamaki FUKATA, et al.
		US			

			F	OREIGN PA	TENT DOCUM	ENTS	
Examiner Cite Initials* No.1	Cite	Foreign Patent Document			Publication Date	Name of Patentee or	Translation ⁶
		Country Code ³	Number ⁴	Kind Code ⁵ (if known)	MM-DD-YYYY	Applicant of Cited Document	
		JP	11-200090	A	07-27-1999	CANON INC.	Abstract
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		NON PATENT LITERATURE DOCUMENTS	·
Examiner Initials*	Cite No.1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city, and/or country where published.	Translation ⁶
		David G. W. GOAD, et al., "Colloidal Metal in Aluminum-Oxide", J. APPL. PHYS. Vol. 49, No. 5, pp. 2929-2934, May 1978	
		A. ANDERSSON, et al., "Nickel Pigmented Anodic Aluminum Oxide for Selective Absorption of Solar Energy", J. APPL. PHYS., Vol. 51, No. 1, pp. 754-764, January 1980	
		Masashi NAKAO, et al., "GaAs and InP Nanohole Arrays Fabricated by Reactive Beam Etching Using Highly Ordered Alumina Membranes", JPN. J. APPL. PHYS., Vol. 38, pp. 1052-1055, Part 1, No. 2B, February 1999	
			

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^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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